Inventor(s): David L. Adler Atty Docket No. 10011.001110 (P0979)

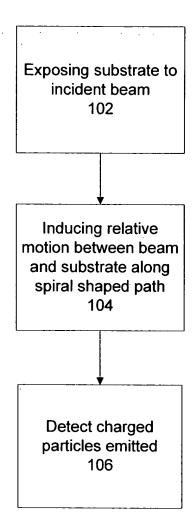


FIG. 1

High-Speed Inspection of Flat Substrate with Underlying
Visible Topology
Inventor(s): David L. Adler
Atty Docket No. 10011.001110 (P0979)

Exposing substrate to incident beam using column 202

Detecting emitted charged particles using multiple detector elements outside column 204

FIG. 2

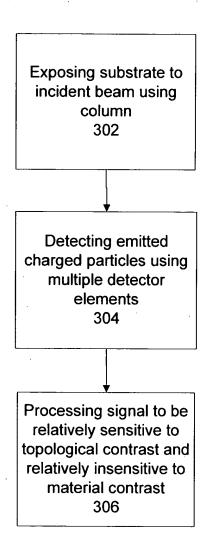


FIG. 3

High-Speed Inspection of Flat Substrate with Underlying
Visible Topology
Inventor(s): David L. Adler
Atty Docket No. 10011.001110 (P0979)

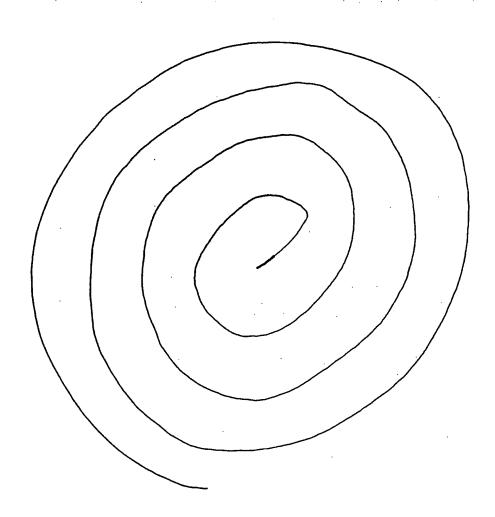
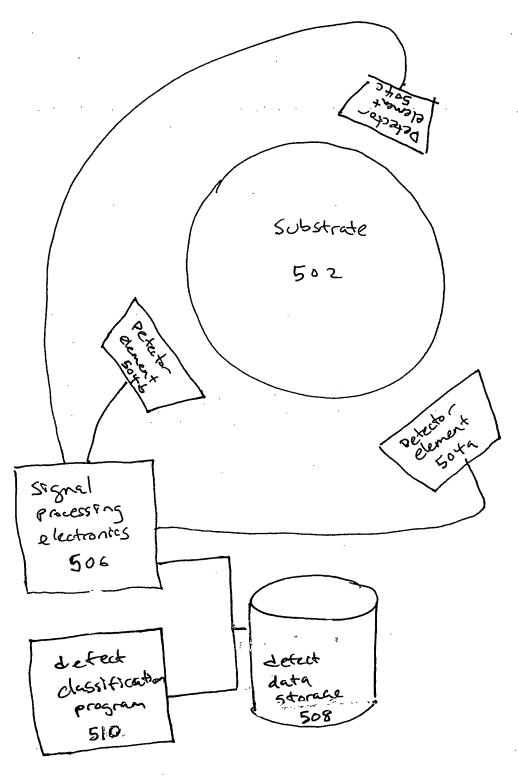


FIG.4

High-Speed Inspection of Flat Substrate with Underlying Visible Topology

Inventor(s): David L. Adler Atty Docket No. 10011.001110 (P0979)



FIG, 5